

<b>Notice of References Cited</b>	Application/Control No. 10/730,295	Applicant(s)/Patent Under Reexamination CHOI, KYEONG KEUN	
	Examiner David S. Blum	Art Unit 2813	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,972,758 A	10-1999	Liang, Chunlin	438/294
	B	US-6,642,557 B2	11-2003	Liang, Chunlin	257/213
	C	US-6,841,452 B2	01-2005	Tanaka, Hiroyuki	438/424
	D	US-6,232,202 B1	05-2001	Hong, Gary	438/424
	E	US-6,770,563 B2	08-2004	Huang et al.	438/702
	F	US-6,716,757 B2	04-2004	Lin et al.	438/705
	G	US-5,915,192	06-1999	Liaw et al.	438/435
	H	US-6,015,985 A	01-2000	Ho et al.	257/301
	I	US-6,806,188 B2	10-2004	Kim, Si Youn	438/675
	J	US-6,806,188 B2	10-2004	Kim, Si Youn	438/675
	K	US-4,352,724	10-1982	Sugishima et al.	204/192.37
	L	US-			
	M	US-			

#### FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Stanley Wolf SILICON PROCESSING FOR THE VSLI ERA Vol. 2 Lattice Press 1990 pages 53 and 198
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.